

	Hits	Search Text	DBs
1	624	ETCHS3 and ("SAME" EQUAL EQUIVALENT SIMILAR CLOSE) NEAR (RATE SPEED))	USPAT, US-PGPUB, EPO, JPO, DERWENT, IBM TCB
2	853	ETCHS3 and ("SAME" EQUAL EQUIVALENT SIMILAR CLOSE) NEAR (RATE SPEED))) and ETCHS3 near (si silicon polysilicon doped)	USPAT, US-PGPUB, EPO, JPO, DERWENT, IBM TCB
3	151	ETCHS3 and ("SAME" EQUAL EQUIVALENT SIMILAR CLOSE) NEAR (RATE SPEED))) and ETCHS3 near (dopos S2type)	USPAT, US-PGPUB, EPO, JPO, DERWENT, IBM TCB
4	920	ETCHS3 and ("SAME" EQUAL EQUIVALENT SIMILAR CLOSE) NEAR (RATE SPEED))) and ETCHS3 near (si silicon polysilicon doped) (ETCHS3 and ("SAME" EQUAL EQUIVALENT SIMILAR CLOSE) NEAR (RATE SPEED))) and ETCHS3 near (dopos S2type))	USPAT, US-PGPUB, EPO, JPO, DERWENT, IBM TCB
5	175	((ETCHS3 and ("SAME" EQUAL EQUIVALENT SIMILAR CLOSE) NEAR (RATE SPEED))) and ETCHS3 near (si silicon polysilicon doped) (ETCHS3 and ("SAME" EQUAL EQUIVALENT SIMILAR CLOSE) NEAR (RATE SPEED))) and ETCHS3 near (dopos S2type)) and fluorine CF4 "CF sub 4" and chlorine HCl CL2 "Cl sub 2")	USPAT, US-PGPUB, EPO, JPO, DERWENT, IBM TCB
6	52	((ETCHS3 and ("SAME" EQUAL EQUIVALENT SIMILAR CLOSE) NEAR (RATE SPEED))) and ETCHS3 near (si silicon polysilicon doped) (ETCHS3 and ("SAME" EQUAL EQUIVALENT SIMILAR CLOSE) NEAR (RATE SPEED))) and ETCHS3 near (dopos S2type)) and fluorine CF4 "CF sub 4" and chlorine HCl CL2 "Cl sub 2") and etchS3 same fluorine CF4 "CF sub 4" same chlorine HCl CL2 "Cl sub 2") and fluorine CF4 "CF sub 4" near chlorine HCl CL2	USPAT, US-PGPUB, EPO, JPO, DERWENT, IBM TCB
7	107	((ETCHS3 and ("SAME" EQUAL EQUIVALENT SIMILAR CLOSE) NEAR (RATE SPEED))) and ETCHS3 near (si silicon polysilicon doped) (ETCHS3 and ("SAME" EQUAL EQUIVALENT SIMILAR CLOSE) NEAR (RATE SPEED))) and ETCHS3 near (dopos S2type)) and fluorine CF4 "CF sub 4" and chlorine HCl CL2 "Cl sub 2") and etchS3 same fluorine CF4 "CF sub 4" same chlorine HCl CL2 "Cl sub 2")	USPAT, US-PGPUB, EPO, JPO, DERWENT, IBM TCB
8	55	((ETCHS3 and ("SAME" EQUAL EQUIVALENT SIMILAR CLOSE) NEAR (RATE SPEED))) and ETCHS3 near (si silicon polysilicon doped) (ETCHS3 and ("SAME" EQUAL EQUIVALENT SIMILAR CLOSE) NEAR (RATE SPEED))) and ETCHS3 near (dopos S2type)) and fluorine CF4 "CF sub 4" and chlorine HCl CL2 "Cl sub 2") and etchS3 same fluorine CF4 "CF sub 4" same chlorine HCl CL2 "Cl sub 2") and etchS3 same fluorine CF4 "CF sub 4" same chlorine HCl CL2 "Cl sub 2") and fluorine CF4 "CF sub 4" near chlorine HCl CL2 "Cl sub 2")	USPAT, US-PGPUB, EPO, JPO, DERWENT, IBM TCB
9	45	((ETCHS3 and ("SAME" EQUAL EQUIVALENT SIMILAR CLOSE) NEAR (RATE SPEED))) and ETCHS3 near (si silicon polysilicon doped) (ETCHS3 and ("SAME" EQUAL EQUIVALENT SIMILAR CLOSE) NEAR (RATE SPEED))) and ETCHS3 near (dopos S2type)) and fluorine CF4 "CF sub 4" and chlorine HCl CL2 "Cl sub 2") and etchS3 same fluorine CF4 "CF sub 4" same chlorine HCl CL2 "Cl sub 2") and etchS3	USPAT, US-PGPUB, EPO, JPO, DERWENT, IBM TCB
		((ETCHS3 and ("SAME" EQUAL EQUIVALENT SIMILAR CLOSE) NEAR (RATE SPEED))) and ETCHS3 near (si silicon polysilicon doped) (ETCHS3 and ("SAME" EQUAL EQUIVALENT SIMILAR CLOSE) NEAR (RATE SPEED))) and ETCHS3 near (dopos S2type)) and fluorine CF4 "CF sub 4" and chlorine HCl CL2 "Cl sub 2") and etchS3 same fluorine CF4 "CF sub 4" same chlorine HCl CL2 "Cl sub 2")	
10	27	CL2 "Cl sub 2") and etchS3 and ("S-Me" EQUAL EQUIVALENT SIMILAR CLOSE) NEAR (RATE SPEED))) and ETCHS3 near (si silicon polysilicon doped) (ETCHS3 and ("SAME" EQUAL EQUIVALENT SIMILAR CLOSE) NEAR (RATE SPEED))) and ETCHS3 near (dopos S2type)) and fluorine CF4 "CF sub 4" and chlorine HCl CL2 "Cl sub 2") and etchS3 same fluorine CF4 "CF sub 4" same chlorine HCl CL2 "Cl sub 2") and etchS3 same fluorine CF4 "CF sub 4" same chlorine HCl CL2 "Cl sub 2")	US-PGPUB, EPO, JPO, DERWENT, IBM TCB

	Hits	Search Text	DBs
11	16	(((((ETCHS3 and ("SAME" EQUAL EQUIVALENT SIMILAR CLOSE) NEAR (RATE SPEED))) and ETCHS3 near (si silicon polysilicon doped)) ((ETCHS3 and ("SAME" EQUAL EQUIVALENT SIMILAR CLOSE) NEAR (RATE SPEED)) and ETCHS3 near (dops \$2type))) and (fluorine CF4 "CF sub 4") and (chlorine HCl CL2 "Cl sub 2")) and (etchS3 same (fluorine CF4 "CF sub 4") same (chlorine HCl CL2 "Cl sub 2")) and (etchS3 and ("SAME" EQUAL EQUIVALENT SIMILAR CLOSE) NEAR (RATE SPEED)) and ETCHS3 near (si silicon polysilicon doped)) ((ETCHS3 and ("SAME" EQUAL EQUIVALENT SIMILAR CLOSE) NEAR (RATE SPEED)) and ETCHS3 near (dops \$2type))) and (fluorine CF4 "CF sub 4") and (chlorine HCl CL2 "Cl sub 2")) and (etchS3 same (fluorine CF4 "CF sub 4") same (chlorine HCl CL2 "Cl sub 2")) and ("SAME" EQUAL EQUIVALENT SIMILAR CLOSE) NEAR (RATE SPEED)) and ETCHS3 near (si silicon polysilicon doped)) ((ETCHS3 and ("SAME" EQUAL EQUIVALENT SIMILAR CLOSE) NEAR (RATE SPEED)) and ETCHS3 near (dops \$2type)) and (fluorine CF4 "CF sub 4") and (chlorine HCl CL2 "Cl sub 2")) and (etchS3 same (fluorine CF4 "CF sub 4") same (chlorine HCl CL2 "Cl sub 2")) and (fluorine CF4 "CF sub 4") near (chlorine HCl CL2 "Cl sub 2"))	USPAT US-PGPUB EPO JPO DERWENT IBM TDB
12	404	etchS3 same doped same undoped same rate	USPAT US-PGPUB EPO JPO DERWENT IBM TDB
13	5	etchS3 same doped same undoped same rate) and ("SAME" EQUAL EQUIVALENT SIMILAR CLOSE) NEAR (RATE SPEED)) and (fluorine CF4 "CF sub 4") near (chlorine HCl CL2 "Cl sub 2"))	USPAT US-PGPUB EPO JPO DERWENT IBM TDB
14	5	etchS3 same doped same undoped same rate) and ("SAME" EQUAL EQUIVALENT SIMILAR CLOSE) NEAR (RATE SPEED)) and (fluorine CF4 "CF sub 4") same (chlorine HCl CL2 "Cl sub 2")) not ((etchS3 same doped same undoped same rate) and ("SAME" EQUAL EQUIVALENT SIMILAR CLOSE) NEAR (RATE SPEED)) and (fluorine CF4 "CF sub 4") near (chlorine HCl CL2 "Cl sub 2"))	USPAT US-PGPUB EPO JPO DERWENT IBM TDB
15	48	etchS3 same doped same undoped same rate) and ("SAME" EQUAL EQUIVALENT SIMILAR CLOSE) NEAR (RATE SPEED))	USPAT US-PGPUB EPO JPO DERWENT IBM TDB